1. Buyer

1.1 Buyer

Official name:	Universiteit Twente
Legal type of the buyer:	Body governed by public law
Activity of the contracting authority:	Education

2. Procedure

2.1 Procedure

Title:	European Tender Two Parallel Plate Plasma-enhanced Chemical Vapor Deposition (PECVD) Systems
Description:	The University of Twente is tendering to purchase two new Plasma-Enhanced Chemical Vapor Deposition systems. The MESA+ Institute will invest in two new systems for deposition of (doped) dielectric thin films to upgrade and reinforce their state-of-the-art thin film technology and processing capacity. The systems will be used for moderate-temperature deposition of low stress thin films. For the following materials: silicon dioxide (SiO2) boron-doped SiO2 (BSG) phosphorus-doped SiO2 (PSG) boron-phosphorus-doped SiO2 (BPSG) low-stress silicon nitride (SiNx) silicon oxynitride (SiOxNy) amorphous silicon (aSi)
Procedure identifier:	f7dc0cc9-05fc-482f-812d-aeac3a214c4f
Previous notice:	e1343fc7-7bb0-4c37-9241-20c4935893ef-01
Internal identifier:	EB-OUT 6685
Type of procedure:	Open
The procedure is accelerated:	no

2.1.1 Purpose

Main nature of the contract :	Supplies
Main classification (cpv):	38000000 Laboratory, optical and precision equipments (excl. glasses)

2.1.2 Place of performance

Country:	Netherlands

Anywhere in the given country

Additional information:	Zie documentatie

2.1.3 Value

Estimated value excluding VAT:	800 000 Euro

2.1.4 General information

Legal basis:

Directive 2014/24/EU

5. Lot

5.1 Lot technical ID: LOT-0000

Title:	European Tender Two Parallel Plate Plasma-enhanced Chemical Vapor Deposition (PECVD) Systems

Rijksoverheid

Description:	The University of Twente is tendering to purchase two new Plasma-Enhanced Chemical Vapor Deposition systems. The MESA+ Institute will invest in two new systems for deposition of (doped) dielectric thin films to upgrade and reinforce their state-of-the-art thin film technology and processing capacity. The systems will be used for moderate-temperature deposition of low stress thin films. For the following materials: silicon dioxide (SiO2) boron-doped SiO2 (BSG) phosphorus-doped SiO2 (PSG) boron-phosphorus-doped SiO2 (BPSG) low-stress silicon nitride (SiNx) silicon oxynitride (SiOxNy) amorphous silicon (aSi)
Internal identifier:	EB-OUT 6685

5.1.1 Purpose

Main nature of the contract :	Supplies
Main classification (cpv):	38000000 Laboratory, optical and precision equipments (excl. glasses)

5.1.2 Place of performance

Country:	Netherlands

Anywhere in the given country

Additional information:	Zie documentatie

5.1.3 Estimated duration

Start date:	18/08/2025
Duration end date:	01/07/2026

5.1.5 Value

Estimated value excluding VAT:	800 000 Euro

5.1.6 General information

Procurement Project not financed with EU Funds.

The procurement is covered by the Government Procurement Agreement (GPA):	no

5.1.10 Award criteria

Criterion:	
Type:	Quality
Name:	Wishes
Description:	See descriptive document
Category of award threshold criterion:	Weight (points, exact)
Award criterion number:	50
Criterion:	

Rijksoverheid

Type:	Quality
Name:	Sustainability
Description:	See descriptive document
Category of award threshold criterion:	Weight (points, exact)
Award criterion number:	20

Criterion:

Type:	Price
Name:	Price
Description:	See descriptive document
Category of award threshold criterion:	Weight (points, exact)
Award criterion number:	30

5.1.15 Techniques

Framework agreement:

No framework agreement

Information about the dynamic purchasing system:

No dynamic purchase system

5.1.16 Further information, mediation and review

Review organisation:	Rechtbank Overijssel
Information about review deadlines:	See descriptive document
Organisation providing more information on the review procedures:	Universiteit Twente

6. Results

Value of all contracts awarded in this notice:	870 000 Euro

6.1 Result lot Identifier: LOT-0000

At least one winner was chosen.

6.1.2 Information about winners

Winner:

Official name: Oxford Instruments GmbH

Tender:

Tender

Rijksoverheid

identifier:	EB-OUT 6685
Identifier of lot or group of lots:	LOT-0000
Value of the tender:	870 000 Euro
Subcontracting :	No

Contract information:

Identifier of the contract:	EB-OUT 6685
Title:	Two Parallel Plate Plasma-enhanced Chemical Vapor Deposition (PECVD) Systems
Date of the conclusion of the contract:	25/08/2025

6.1.4 Statistical information

Summary of the review requests the buyer received:

Number of complainants:	0

Received tenders or requests to participate:

Type of received submissions:	Tenders submitted electronically
Number of tenders or requests to participate received:	1

8. Organisations

8.1 ORG-0001

Official name:	Universiteit Twente
Registration number:	50130536
Postal address :	Drienerlolaan 5
Town:	Enschede
Postcode:	7522NB
Country subdivision (NUTS):	Twente (NL213)
Country:	Netherlands
Contact point:	Camilio Delfgaauw
Email:	c.delfgaauw@utwente.nl
Telephone:	+31534891512
Internet address:	https://www.utwente.nl
Buyer profile:	https://s2c.mercell.com/buyer/16033

Roles of this organisation:

Buyer

Organisation providing more information on the review procedures

Rijksoverheid

8.1 ORG-0002

Official name:	Rechtbank Overijssel
Registration number:	82940525
Town:	Almelo
Postcode:	7607 GB
Country subdivision (NUTS):	Twente (NL213)
Country:	Netherlands
Email:	communicatie.rb-ove@rechtspraak.nl
Telephone:	(+31)0883611042

Roles of this organisation:

Review organisation

8.1 ORG-0003

Official name:	Oxford Instruments GmbH
Size of the economic operator:	Large
Registration number:	hrb21599
Postal address :	Borsigstr. 15A
Town:	Wiesbaden
Postcode:	65205
Country subdivision (NUTS):	Wiesbaden, Kreisfreie Stadt (DE714)
Country:	Germany
Contact point:	Raphael Clemens
Email:	GER-PT_Tenders@oxinst.com
Telephone:	+491754879981
Internet address:	https://www.oxinst.com

Roles of this organisation:

Tenderer

Winner of these lots: LOT-0000

Notice information

Notice identifier /version:	b00f669b-6182-4678-b644-96d2f7c1d5bb - 01
Form type:	Result
Notice type:	Contract or concession award notice – standard regime
Notice dispatch date:	06/02/2026 13:05 +00:00
Notice dispatch date (eSender):	06/02/2026 13:05 +00:00

Rijksoverheid

Languages in which this notice is officially available:	English

Rijksoverheid